

Resource Summary Report

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Oxford: PlasmaPro 80 ICP Plasma Technology

RRID:SCR_020377

Type: Tool

Proper Citation

Oxford: PlasmaPro 80 ICP Plasma Technology (RRID:SCR_020377)

Resource Information

URL: <https://plasma.oxinst.com/products/icp-etching/80icp>

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Description: PlasmaPro 80 ICP is compact, small footprint system offering ICP etch solutions with open loading. Open load design allows fast wafer loading and unloading, ideal for research, prototyping and low volume production. It enables high performance processes using optimised electrode cooling and substrate temperature control.

Resource Type: instrument resource

Keywords: Oxford, Plasma Technology, Instrument, Resource equipment, Equipment, USEDit,

Availability: Commercially available

Resource Name: Oxford: PlasmaPro 80 ICP Plasma Technology

Resource ID: SCR_020377

Alternate IDs: Model_Number_80_ICP

Record Creation Time: 20220129T080350+0000

Record Last Update: 20260808T190152+0000

Ratings and Alerts

No rating or validation information has been found for Oxford: PlasmaPro 80 ICP Plasma Technology.

No alerts have been found for Oxford: PlasmaPro 80 ICP Plasma Technology.

Data and Source Information

Source: [SciCrunch Registry](#)

Usage and Citation Metrics

We have not found any literature mentions for this resource.